

# 제23회 한국반도체학술대회

2016년 2월 22일(월)-24일(수), 강원도 하이원리조트

## B. Patterning 분과

Room I  
육백II(6층)

2016년 2월 24일(수) 10:00-11:40

[WI2-B] Patterning

좌장 : 김현우(한양대학교)

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| WI2-B-1 | 10:10-10:25 | <b>Effect of Etching Gas on Magnetic Tunnel Junction Stacks Etching using Inductively Coupled Plasma Reactive Ion Etching</b><br>Su Min Hwang, Jae Yong Lee, Adrian Adalberto Garay, Ji Hyun Choi, and Chee Won Chung<br><i>Department of Chemistry and Chemical Engineering, Center for Design and Applications of Molecular Catalysts, Inha University</i>   |
| WI2-B-2 | 10:25-10:40 | <b>Impact of Process Parameters on RLS in EUV Resist Simulation for 10-nm Pattern Formation</b><br>Sang-Kon Kim <sup>1,2</sup><br><sup>1</sup> <i>Department of Applied Physics, Hanyang University;</i> <sup>2</sup> <i>Department of Science, Hongik University</i>  |
| WI2-B-3 | 10:40-10:55 | <b>OPC Optimization Techniques for Reducing The Mismatch Between Overlay Metrology and Device Pattern Cell</b><br>Jae-hee Hwang, Shinyoung Kim, Chanha Park, Hyunjo Yang, and Donggyu Yim<br><i>Research and Development Division, SK hynix Inc.</i>   |
| WI2-B-4 | 10:55-11:10 | <b>Investigation on Overlay Analysis using Design Based Metrology Tool</b><br>Sangwoo Kim, Gyoyeon Jo, Sunkeun Ji, Shinyoung Kim, Hyunwoo Kang, Minwoo Park, Jungchan Kim, Chanha Park, Hyunjo Yang, and Donggyu Yim<br><i>Research and Development Division, SK hynix Inc.</i>  |
| WI2-B-5 | 11:10-11:25 | <b>Improving Same Colors Space Distribution in Multi Patterned Layers for Hotspots Reduction.</b><br>Dong-Gyun Kim <sup>1</sup> , Sung-Keun Park <sup>1</sup> , Young-Gook Park <sup>1</sup> , Jae-Seok Yang <sup>1</sup> , Jong-Hyun Lee <sup>1</sup> , Mostafa Shadoufa <sup>2</sup> , and Mohammed Harb <sup>2</sup><br><sup>1</sup> <i>Samsung Electronics Co., Ltd.,</i> <sup>2</sup> <i>Mentor Graphics Corporation, Egypt</i> |
| WI2-B-6 | 11:25-11:40 | <b>High Scan Speed ArF Immersion Scanner 에서 Topcoat-less Resist 가 가져야 할 특성에 관한 연구</b><br>손민석, 류윤정, 오창일, 반근도, 김겸, 박은주, 복철규, 김영식, 곽노정<br><i>Research and Development Division, DRAM Process Group, SK hynix Inc.</i>   |